

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): BIELLAK, STEVE; STOKOWSKI, STANLEY E.; VAEZ-IRAVANI, MEHDI

Assignee: KLA-TENCOR TECHNOLOGIES CORPORATION

Title: SYSTEM AND METHODS FOR A WAFER INSPECTION SYSTEM USING MULTIPLE ANGLES AND MULTIPLE WAVELENGTH ILLUMINATION

Serial No.: ~~09/891,693~~ 09/891,693 Filing Date: June 26, 2002

Examiner: Hao Q. Pham Group Art Unit: 2877

Docket No.: M-10693 US

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OCT 23 2002
OFFICE OF THE SPECIAL PROGRAMS EXAMINER

San Jose, California
July 24, 2002

PETITION FOR EXTENSION OF TIME

Dear Sir:

Applicants respectfully petitions for a three-month extension of time within which to respond to the January 24, 2002 outstanding Office Action, such extension allowing the undersigned until July 24, 2002 to respond.

03 FC-117 320.00

Please charge the amount of \$920.00 as set forth in the enclosed transmittal letter.

Respectfully submitted,


James S. Hsue
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